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	Su	ubstitute for form 1449A/PTO	Application Number			
IN	IFORN	IATION DISCLOSURE	Filing Date	July 20, 2006		
			First Named Inventor	EIN-ELI Yair e	t al	
STATEMENT BY APPLICANT (use as many sheets as necessary)			Group Art Unit	1793		
			Examiner Name	PARVINI Pegah		
Sheet		1 Of 1	Attorney Docket Number	30579		
		OTHER PRIOR ART – NON PATE				
Examiner Initials	Cite No. ¹		um, catalog, etc.) date, page(s), voluments of country where published.	ne-issue number(s),	\mathbf{T}^2	
	1	Response Dated 04 February 2010 to the US Patent and Trademark Office 1				
	2	Abelev et al. "Enhanced Copper Surfa Containing Short-Chain Alkanoic Act 11288, 2007. July	d Potassium Salts", Langmui	r, 23: 11281-		
	3	Abelev et al. "Potassium Sobate Solutions as Copper Chemical Mechanical Sep. 2006 Planarization (CMP) Based Slurries", Electrochimica Acta, 52: 5150-5158, 2007.				
	4	Abelev et al. "Potassium Sorbate - A Electrochemical and Spectroscopic St 2007. February				
	5	Abelev et al. "Reprint of 'Potassium S Mechanical Planarization (CMP) Base 1029, 2007. September	ed Slurries'", Electrochimica	Acta, 53: 1021-		
	6	Ein-Eli et al. "Food Preservatives Ser Corrosion Inhibitors", Electrochemica	ving as Nonselective Metal ar al and Solid-State Letters, 9(1	nd Alloy Nov . 20): B5-B7, 2006 .	05	
	7	Ein-Eli et al. "Review on Copper Che CMP Cleaning in Ultra Large System Perspective", Electrochimica Acta, 52	mical-Mechanical Polishing (Integrated (ULSI) - An Elect	CMP) and Post-		
		<u> </u>				

Signature /Pegan Parvini/ Considered 02/02/2011		/Pegan Parvini/	Date Considered	
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